

# R&D of silicon detectors for HEP experiments

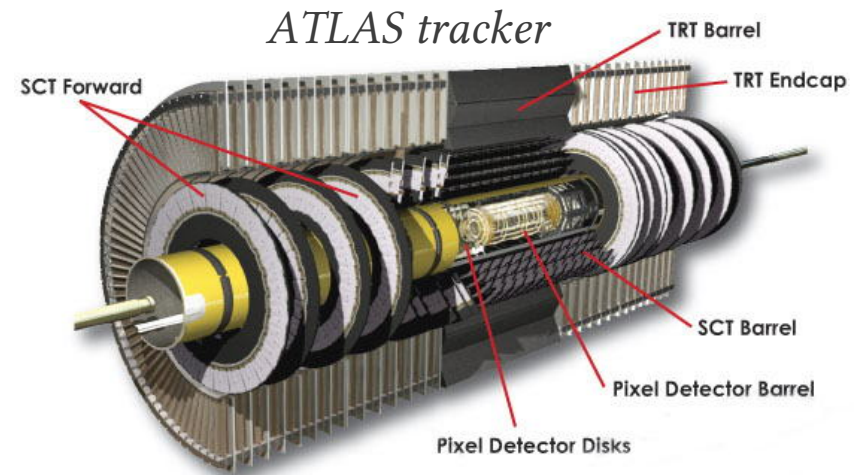
*Irena Dolenc Kittelmann*

ØMIC detector workshop,  
Copenhagen, Denmark, 10. 12. 2012

# Introduction

## Segmented Si detectors in HEP:

- ◆ Used for ~ 30 years
- ◆ Fundamental part of modern HEP experiments (ATLAS, CMS.. at LHC)
- ◆ Fast signal formation times, superior spatial resolution → accurate measurement of charged particle momentum in magnetic field
- ◆ Favorite choice for tracker (**Strip**) and vertex (**Pixel**) detectors → positioned close to interaction point → **radiation damage** (CERN RD50 collaboration)

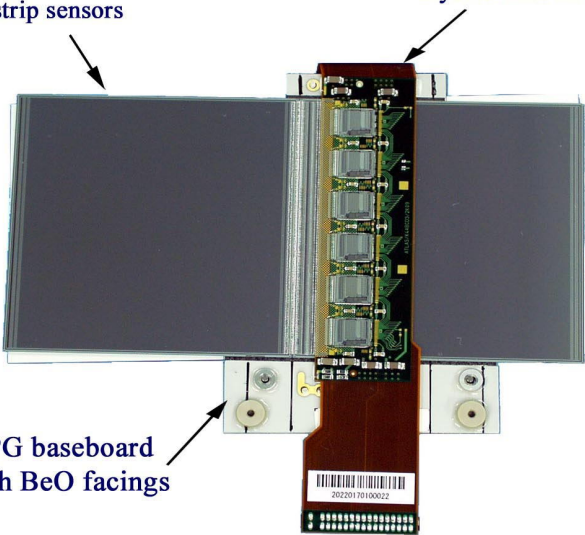


ATLAS strip sensors

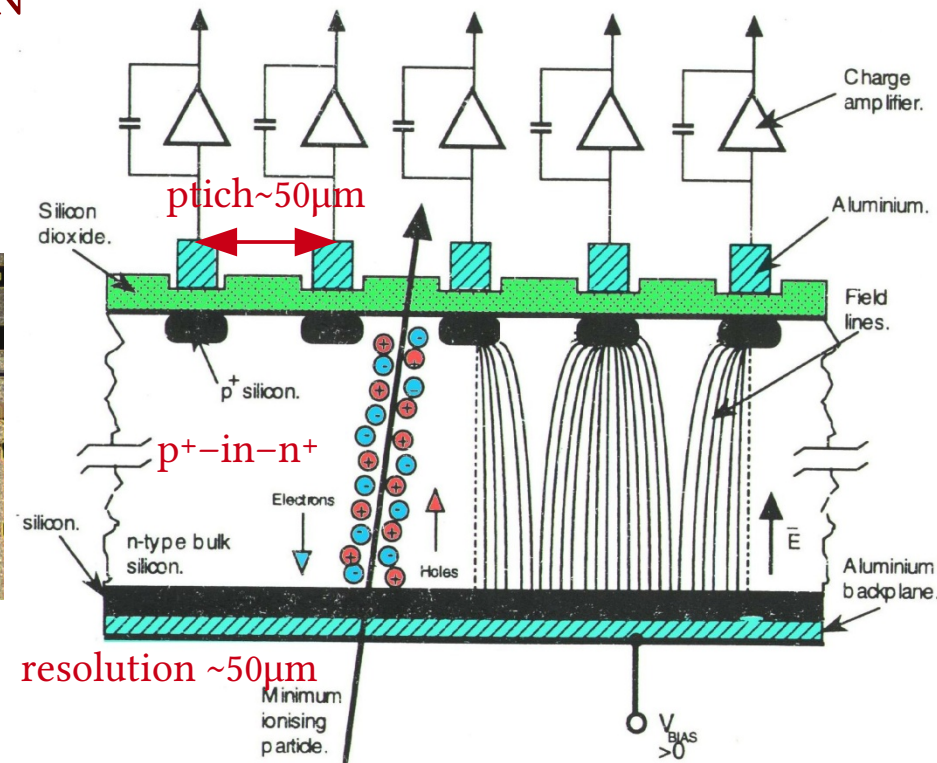
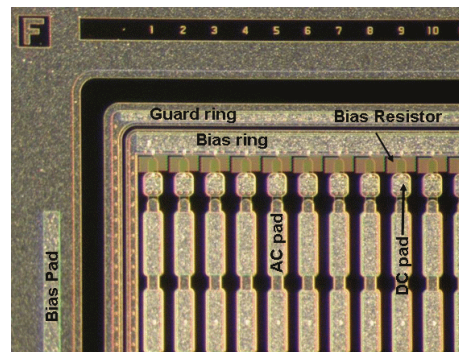
Hybrid with ASICs

Si strip sensors

TPG baseboard with BeO facings

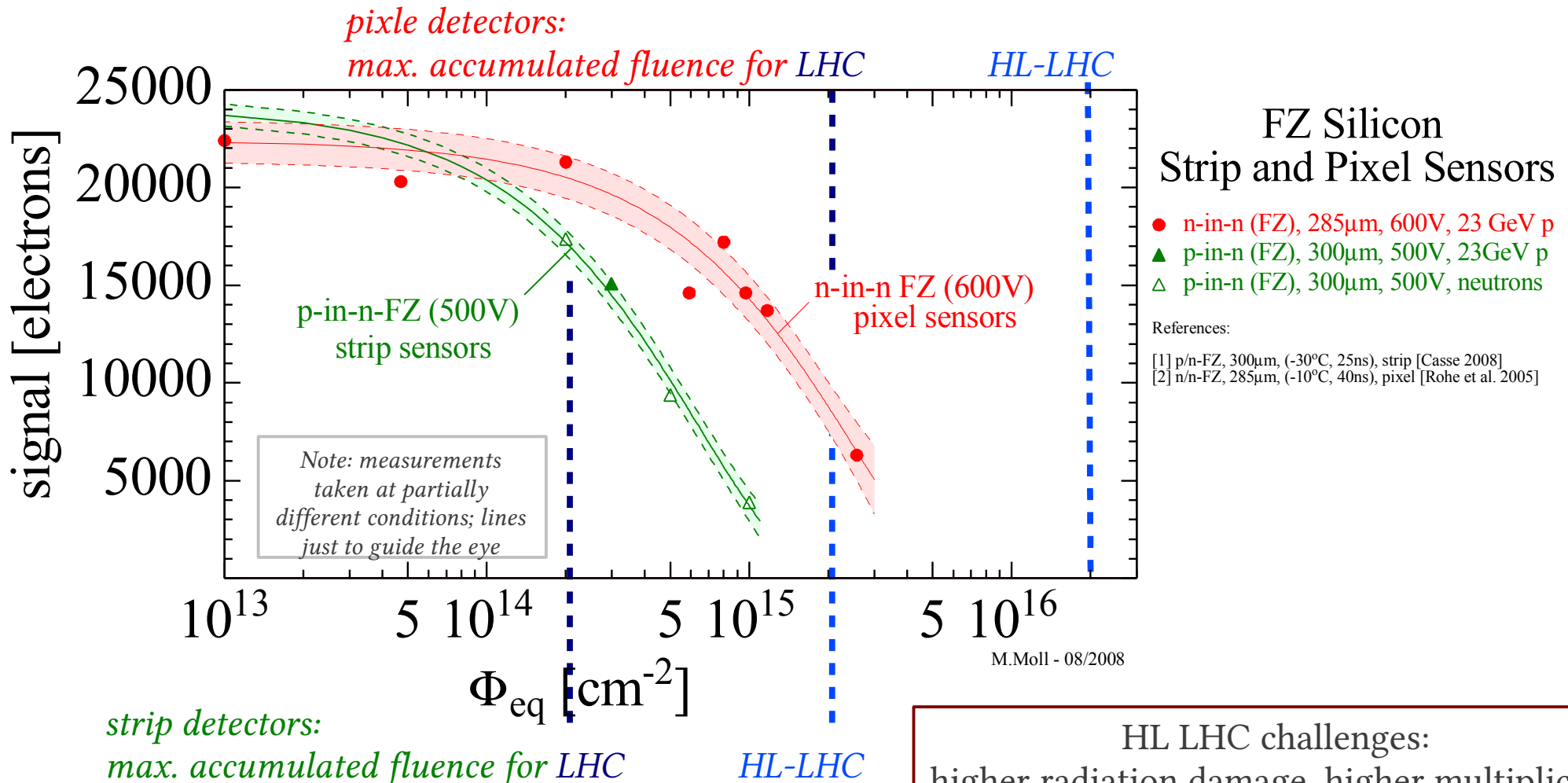


128 mm



# LHC: signal degradation

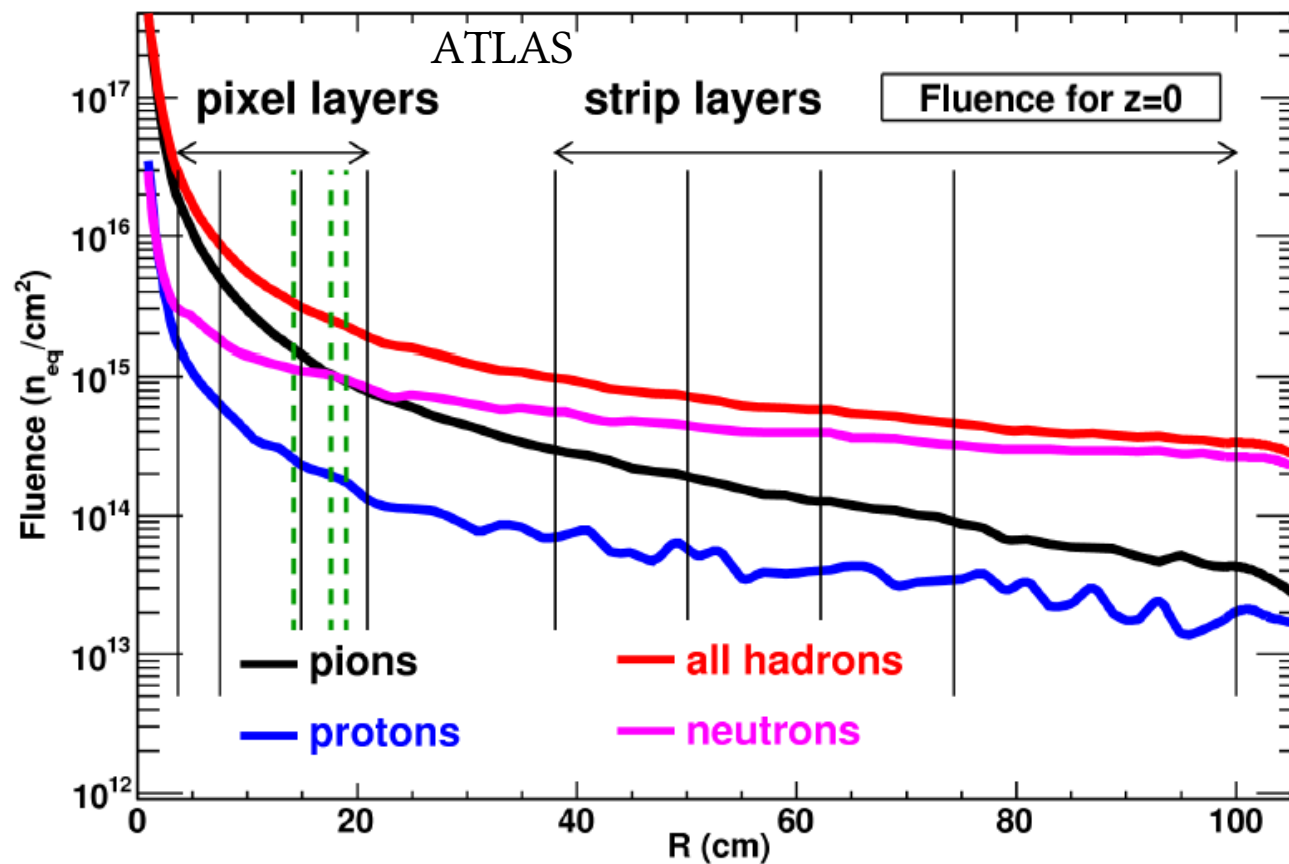
- ♦ LHC:  $L \sim 10^{34} \text{cm}^{-2}\text{s}^{-1}$ , expected to accumulate  $\sim 350 \text{fb}^{-1}$
- ♦ High Luminosity (HL) LHC:  $L = 5 \times 10^{34} \text{cm}^{-2}\text{s}^{-1}$ , aiming to accumulate  $3000 \text{fb}^{-1}$ , planned for  $\sim 2022$



HL LHC challenges:  
higher radiation damage, higher multiplicity,  
triggering, connectivity, cooling, powering

# HL LHC: radiation field

- ◆ Pixel detector:
  - pion radiation damage dominating (neutrons ~10%)
- ◆ Strip detector:
  - damage mostly due to neutrons



ATLAS Radiation Taskforce

[http://atlas.web.cern.ch/Atlas/GROUPS/PHYSICS/RADIATION/RadiationTF\\_document.html](http://atlas.web.cern.ch/Atlas/GROUPS/PHYSICS/RADIATION/RadiationTF_document.html)

# Radiation damage

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## ◆ Surface damage due to IEL (Ionising Energy Loss)

- ◆ accumulation of + charge in the oxide (SiO<sub>2</sub>) and at the Si/SiO<sub>2</sub> interface
- ◆ affects interstrip capacitance (noise), breakdown behavior
- ◆ can be controlled by proper design and manufacturing process

## ◆ Bulk damage due to NIEL (Non Ionising Energy Loss):

- ◆ Results in defects in crystal lattice → new energy levels in the band gap

- ◆  $E_{k,recoil} > 25\text{eV}$ : Si atom displaced out of its lattice site to form interstitial I and vacancy V (Frenkel pair), which can react with other defects to form new type of point defects (VO, V<sub>2</sub>,...)
- ◆  $E_{k,recoil} > 5\text{keV}$ : cluster of displacements possible
- ◆ nuclear reactions: resulting high energy fragments involved in the damage process

- ◆ Comparing the damage:

$\Phi_{eq}$  = equivalent fluence → fluence of 1MeV neutrons needed to cause the same NIEL

- ◆ NIEL scaling hypothesis: “Observed damage in Si bulk scales with energy deposited in the NIEL interactions” → Does not hold in all cases (see later)!

- ◆ Effects on detector performance:

- ◆ Change of *effective dopant concentration*  $N_{eff}$  → change in *full depletion voltage*  $V_{FD}$
- ◆ Increase of *leakage current* (increased noise, high power consumption)
- ◆ Increase of *effective trapping time* (deterioration of *charge collection efficiency CCE*)

# Rad-hard solid state detector development

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## Strategies

- (1) Material engineering
- (2) Detector engineering
- (3) Change of detector operation

### ◆ Defect engineering

- ◆ introduction of defects, impurities in silicon bulk to improve radiation hardness
- ◆ Example: oxygen rich silicon (MCz, Cz, EPI, DOFZ)

### ◆ New materials

- ◆ Silicon Carbide (SiC), Gallium Nitride (GaN), Gallium Arsenide: strong rad. damage observed, no potential for HL-LHC
- ◆ Diamond (CERN RD42 Collaboration)

### ◆ Detector engineering

- ◆ p-type silicon detectors
- ◆ thin detectors, epitaxial detectors
- ◆ 3D detectors
- ◆ Monolithic devices

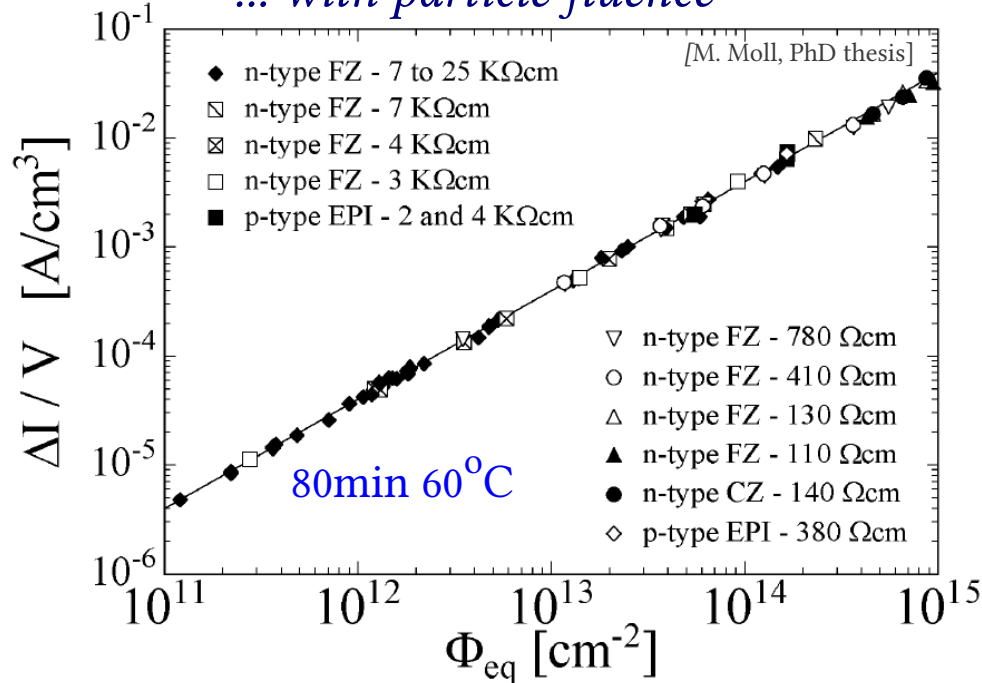
CERN RD39 collaboration  
“Cryogenic Tracking Detectors”  
operation at 100-200K  
to reduce charge loss



# Leakage current

## Change of leakage current

... with particle fluence

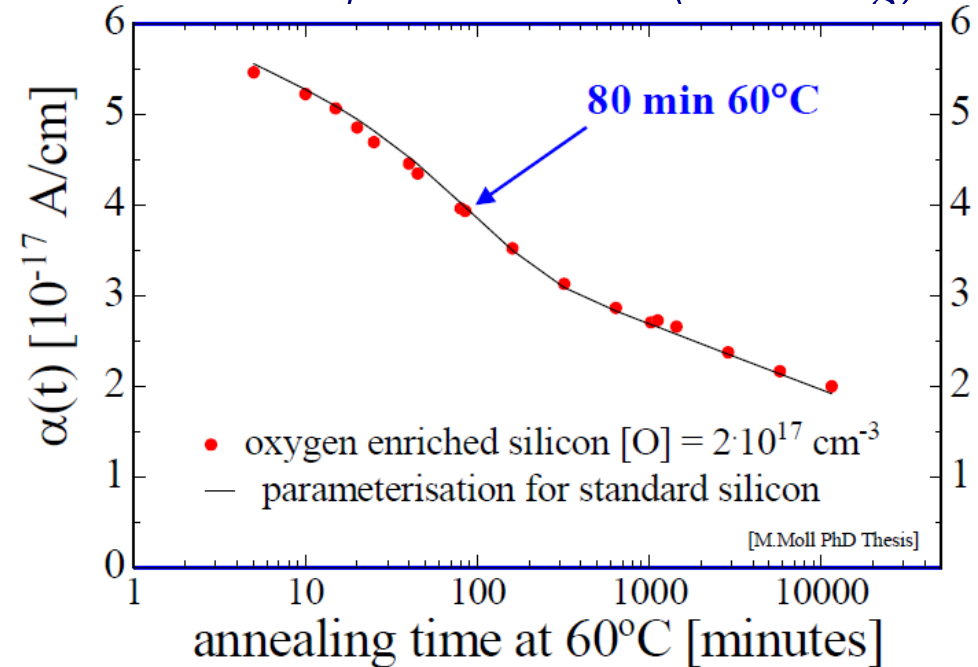


Damage parameter  $\alpha$ :

$$\alpha = \frac{\Delta I}{V \cdot \Phi_{eq}}$$

- ◆ constant over several orders of fluence
- ◆ independent of Si impurity
- ◆ independent of particle type (except  $\gamma$ )  
⇒ can be used for fluence measurement
- ◆ Note: NIEL scaling holds

...with time after irradiation (annealing)



- ◆ Leakage current decreasing with annealing
- ◆ strong temperature dependence

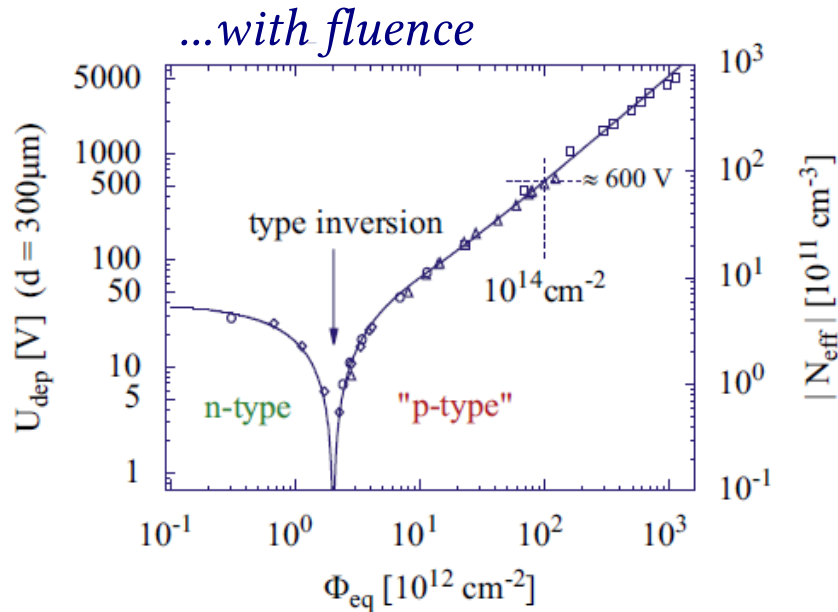
$$I \propto \exp\left(-\frac{E_g}{2k_B T}\right)$$

⇒ cooling during operation needed!

- ◆ Example:  $I(-10^\circ\text{C}) \sim 1/16 I(20^\circ\text{C})$

# Full depletion voltage

Change of  $V_{FD}$  ( $N_{eff}$ ) in standard n-type FZ detectors

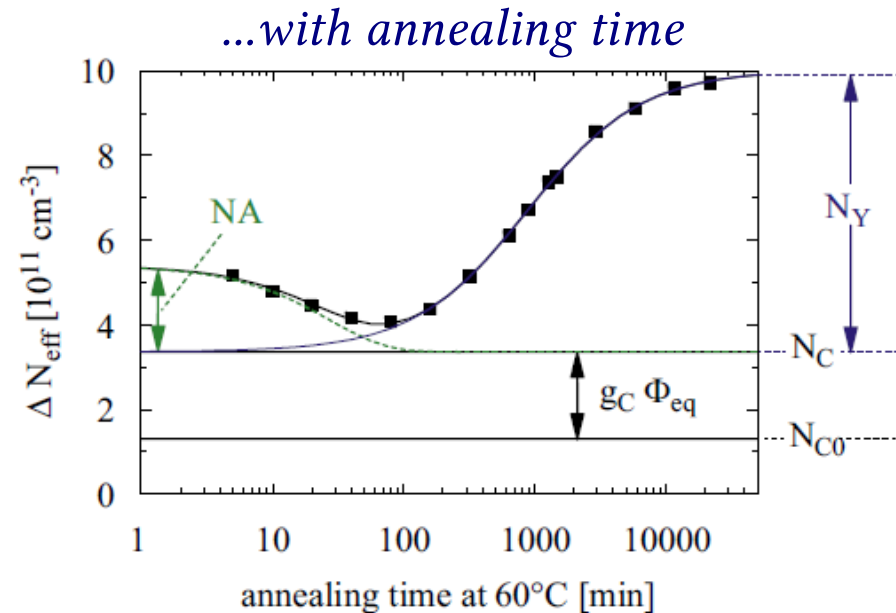


- ◆ “Type inversion”:  $N_{eff}$  changes from **positive** to **negative** (Space Charge Sign Inversion – SCSI)
- ◆ acceptor generation

$$V_{FD} = \frac{e_0 D |N_{eff}|}{2\epsilon_0 \epsilon_{Si}}$$

full depletion  
voltage

effective dopant  
concentration (space  
charge density)



- ◆ Short term: “**Beneficial annealing**”
  - ◆ Long term: “**Reverse annealing**”
    - ◆ time constant depends on temperature:
      - $\sim 500$  years ( $-10^\circ C$ )
      - $\sim 500$  days ( $20^\circ C$ )
      - $\sim 21$  hours ( $60^\circ C$ )
- $\Rightarrow$  Detectors must be cooled even when the experiment is not running!

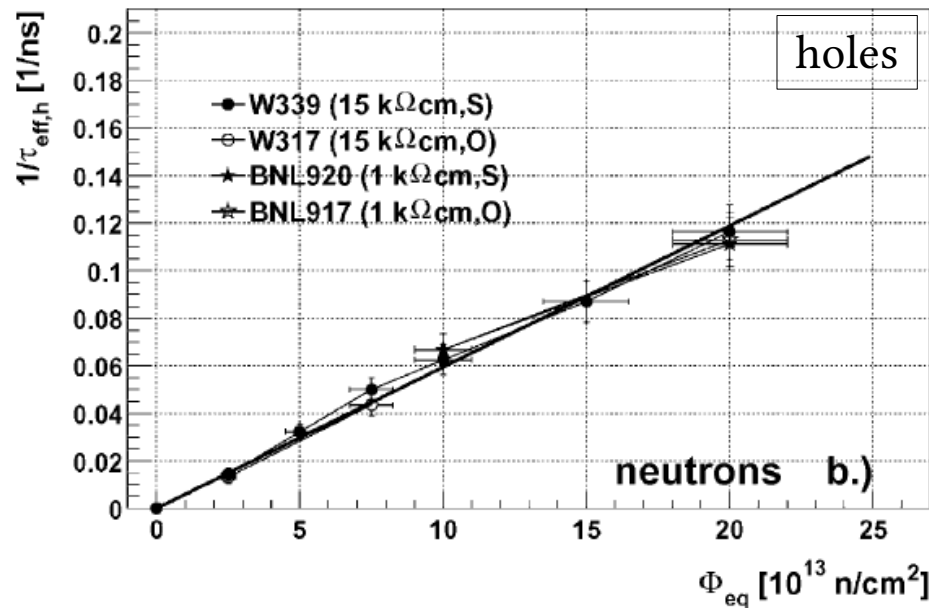


# Trapping

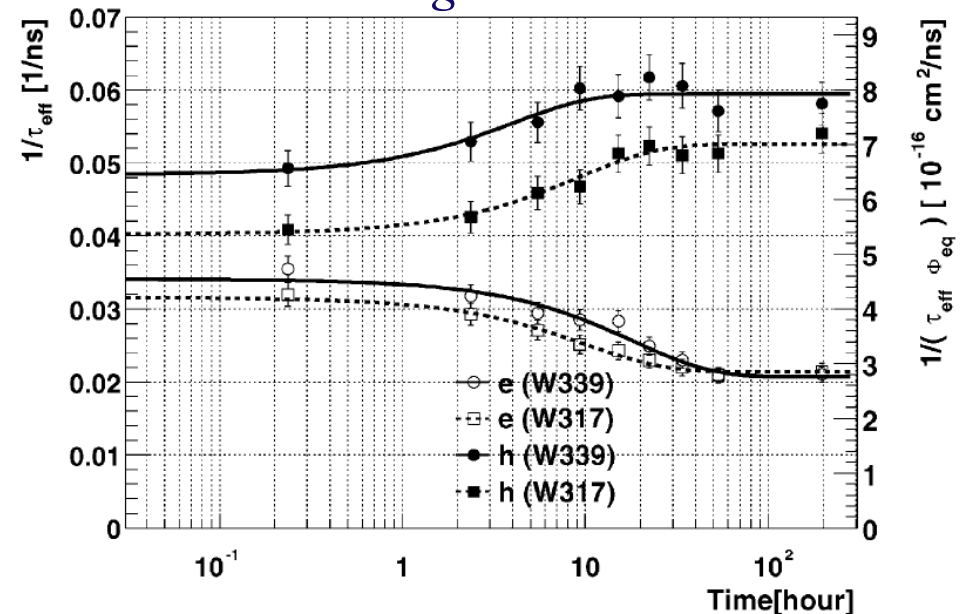
- ◆ CCE degradation due to partial depletion (**underdepletion**) and **trapping**
- ◆ Trapping is described by effective trapping probability for holes and electrons  $1/\tau_{eff\ e,h}$

$$Q_{e,h}(t) = Q_{e,h}(0) \exp\left(-\frac{t}{\tau_{eff\ e,h}}\right) \quad \frac{1}{\tau_{eff\ e,h}} \propto N_{traps}$$

$1/\tau_{eff\ e,h}$  dependence on fluence



... and annealing time



- ◆ **After irradiation:** trapping stronger for holes than electrons; charged hadrons induce more trapping compared to neutrons (NIEL violation)
- ◆ Common to all **materials** after irradiation (apart from  $\gamma$ ): same increase of trapping (electrons and holes) within ~20%
- ◆ **Annealing:** increases trapping for holes, decreased for electrons

# Oxygen rich Si: proton irradiation

Irradiation with 24 GeV/c  
protons

## ◆ Standard FZ silicon

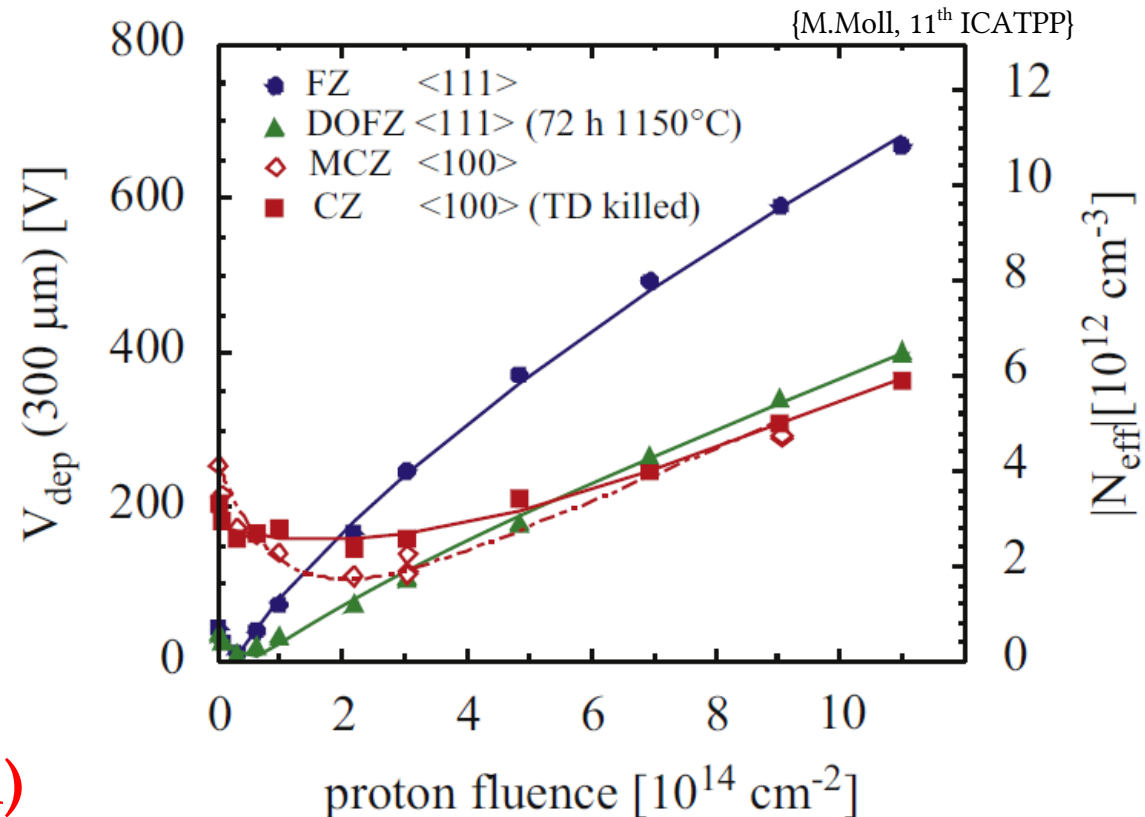
- ◆ type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- ◆ strong  $N_{\text{eff}}$  increase at high fluence

## ◆ DOFZ silicon (is oxygen rich)

- ◆ type inversion at  $\sim 2 \times 10^{13}$  p/cm<sup>2</sup>
- ◆ smaller  $N_{\text{eff}}$  increase at high fluence

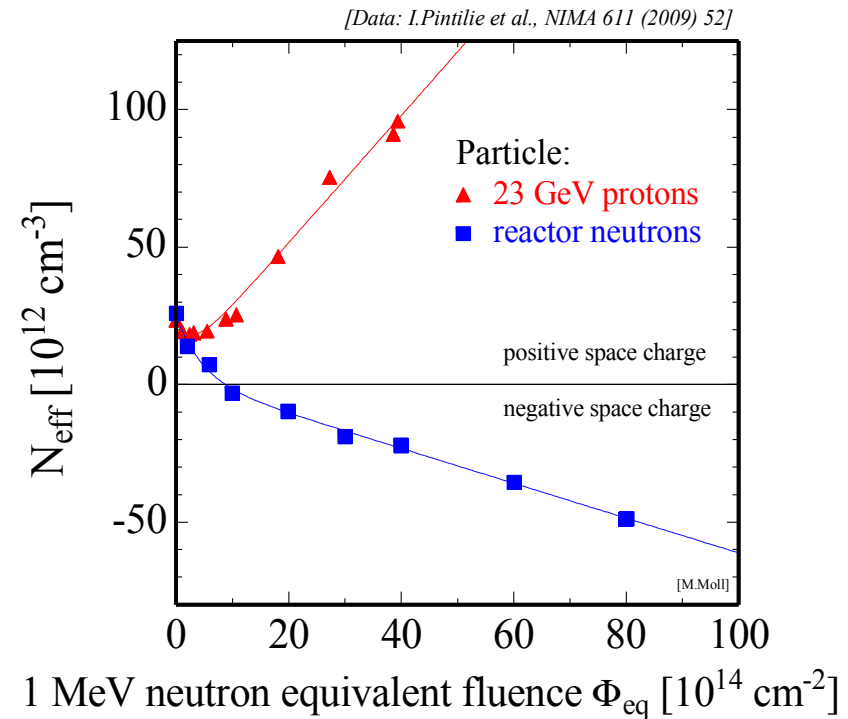
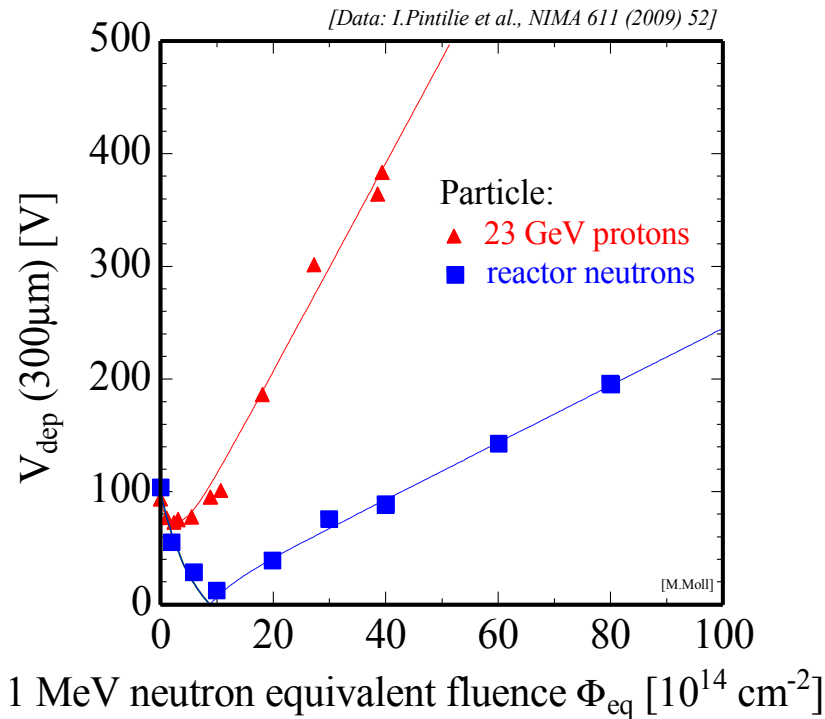
## ◆ Cz, MCz silicon (is oxygen rich)

- ◆ “no type inversion” in the overall fluence range
- ◆ *Comment: there is no “real” type inversion, a more clear understanding of the observed effects is obtained by investigating directly the internal electric field; look for (“double junction” effects, see later)*



# Oxygen rich Si: neutron vs. proton irradiation

EPI silicon (EPI-DO, 72 $\mu\text{m}$ , 170 $\Omega\text{cm}$ ) irradiated with **24GeV/c protons** and reactor neutrons



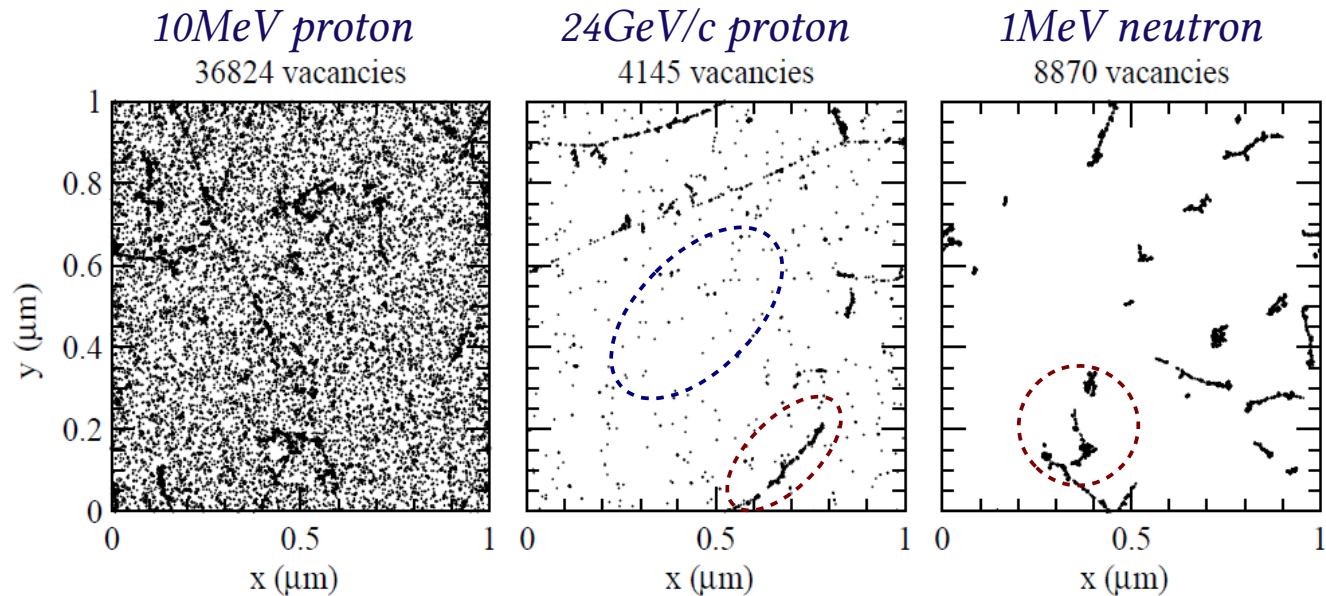
- ◆ SCSI ("Type Inversion") after neutrons but not after protons
- ◆ **Acceptor** generation after **neutron** irradiation (as in standard FZ)
- ◆ **Donor** generation enhanced after **proton** irradiation (only in oxygen rich Si)

# Why the difference in proton and neutron damage?

- ◆ Clusters vs. Point defects:

- ◆ Charged hadrons create less point defects with increasing energy
- ◆ At given particle energy, neutrons create more clusters than protons

Initial distribution of  
vacancies after incidence  
of  $10^{14}$  particles/cm<sup>2</sup>  
[Mika Huhtinen NIMA 491(2002) 194]



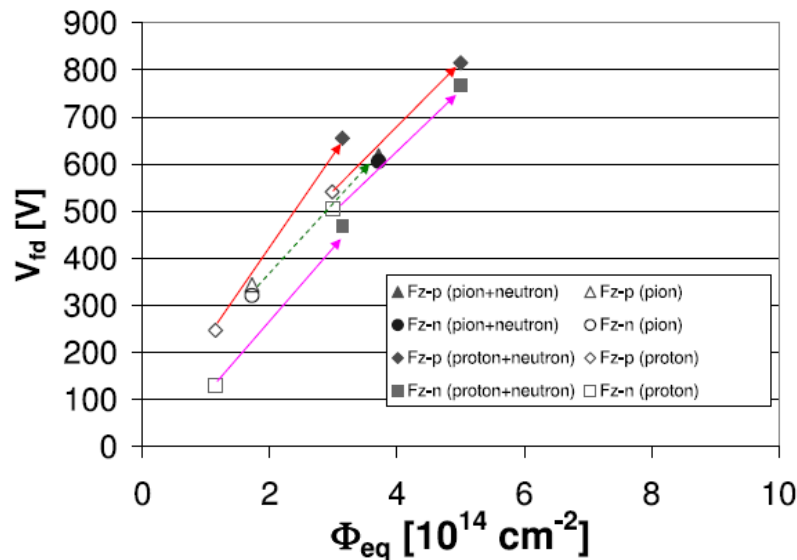
- ◆ A 'simplified' explanation for difference between proton and neutron damage:

- ◆ **Defect clusters** produce predominantly **negative space charge** – acceptors
- ◆ **Point defects** produce predominantly **positive space charge** – donors (in 'oxygen rich' silicon)
- ◆ Comment: note NIEL violation

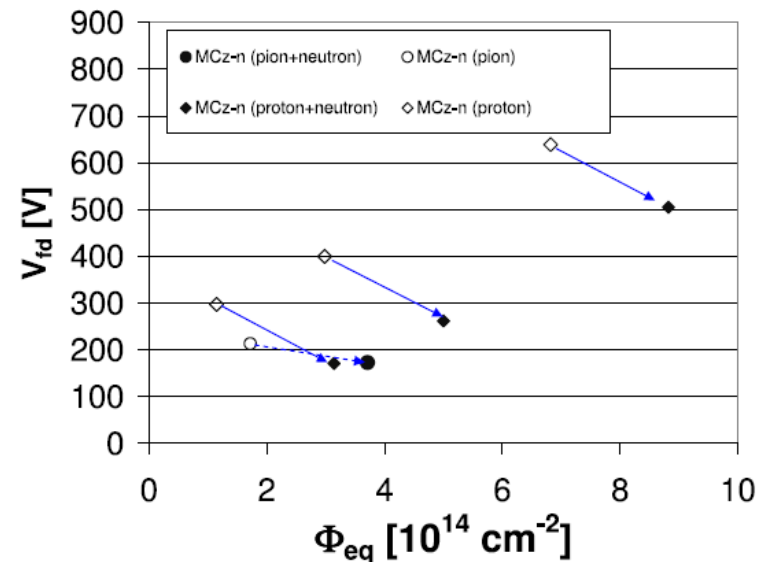
# Oxygen rich Si: mixed irradiations

- ◆ MCz and Fz n-type devices exposed to mixed irradiations:
  - ◆ step 1: proton (or pion) irradiation
  - ◆ step 2: neutron irradiation
- ◆ Result: damage additive! Can we profit from that in real experiment?

FZ-n (low O concentration)  
accumulation of damage

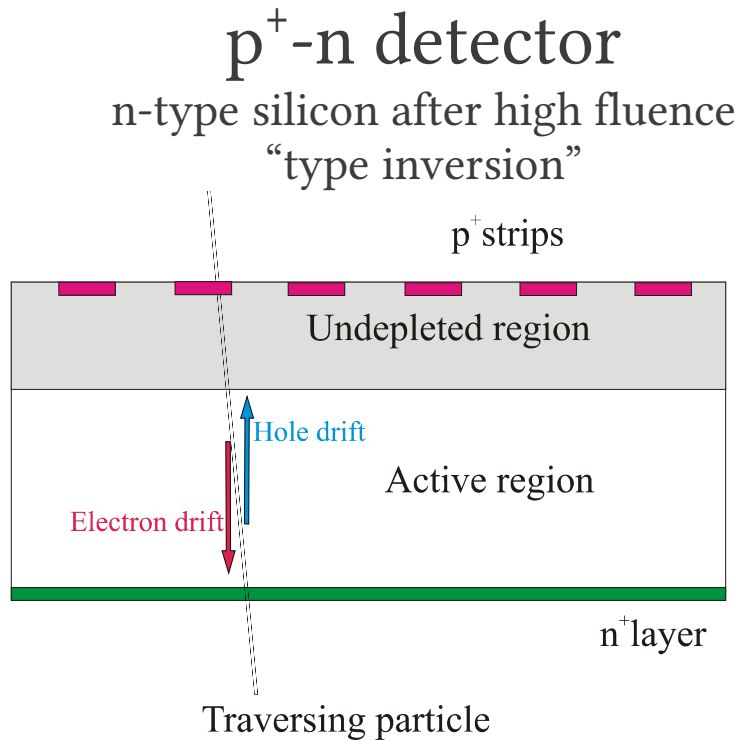


MCz-n (high O concentration)  
compensation of damage



[G.Kramberger et al.,  
NIMA, 609 (2009), p142]

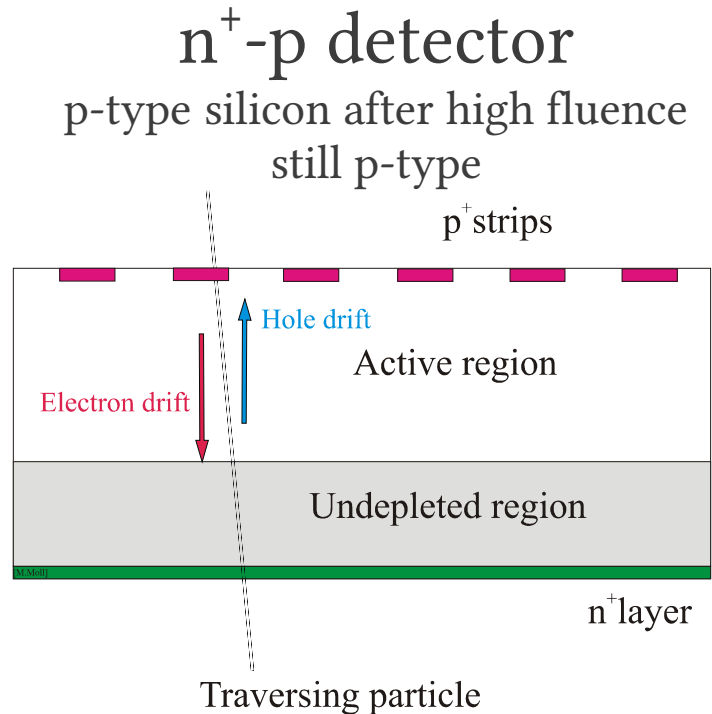
# Device engineering: p-type devices



- ◆ High el. field region on the back (non-segmented side)
- ◆ **Underdepleted**
  - ◆ charge spread (resolution deterioration)
  - ◆ charge loss (CCE deterioration)

## Comment:

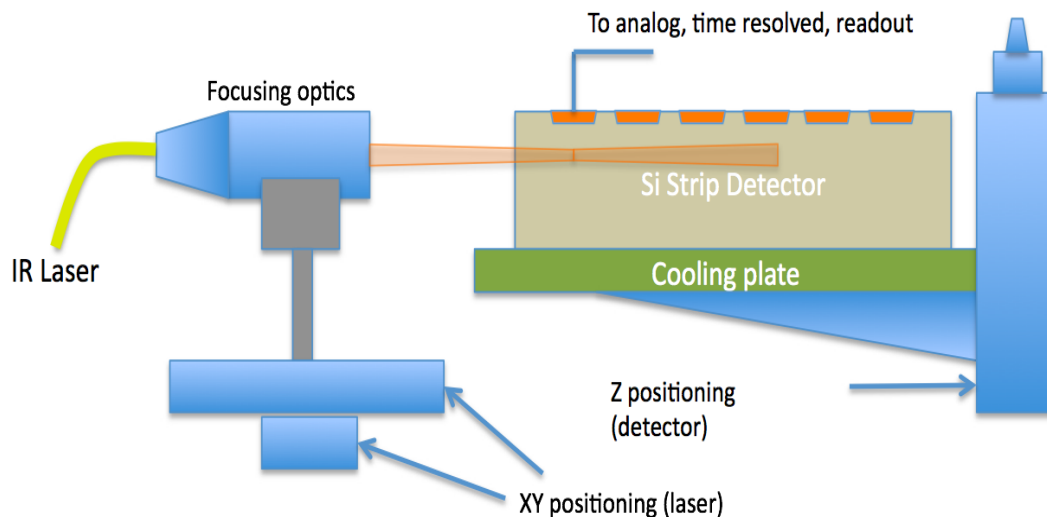
- ✗ *this is just a schematic explanation, reality is much more complex (see next slide)*
- ✗ *Instead of n-on-p also n-on-n devices could be used*



- ◆ High el. field region stays on the front (segmented side → weighting and real field stay aligned)
- ◆ Limited loss of CCE, less deterioration with underdepletion
- ◆ Limited deterioration of resolution
- ◆ Collecting electrons (3-times faster than holes)



# Determination of electric field



## Edge-TCT (transient current technique)

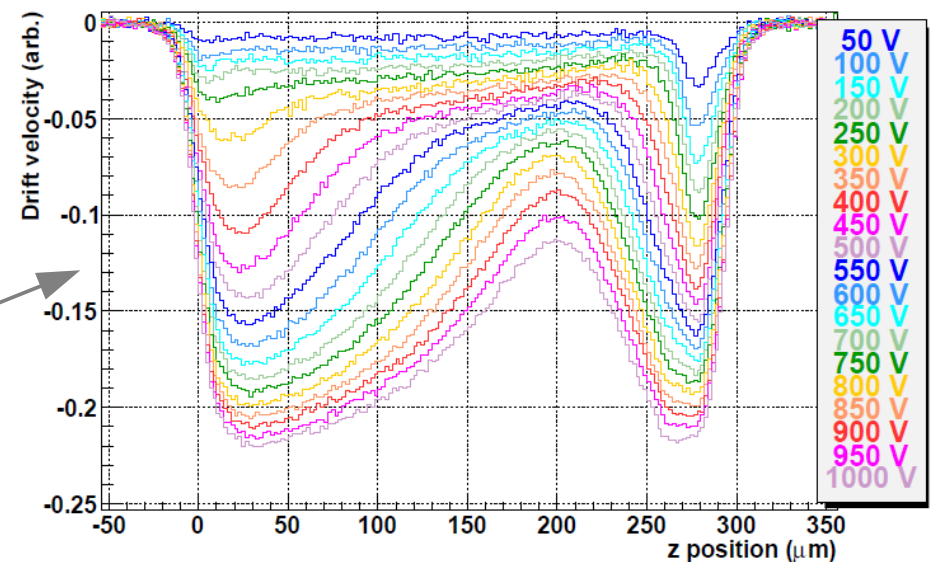
- ◆ Technique pioneered by Gregor Kramberger, Ljubljana [1]
- ◆ Sensor (strip detector) is illuminated with pulsed IR laser from the side, light focused under one of the strips
- ◆ Scan across detector thickness and record induced current signal waveforms as function of depth
- ◆ Reconstruction of drift velocity electric field, detector efficiency (also trapping probability ?) profile across the detector thickness

[1] G. Kramberger et al., IEEE TNS, vol. 57, no. 4, August 2010, p 2294

## Highly irradiated detectors:

- ◆ “Double junction” form of electric field can be observed: field peak both on the back and front
- ◆ Example of drift velocity profile in: MCz-p, irradiated with 24GeV/c protons ( $\Phi_{eq} = 6.2 \times 10^{15} n_{eq}/cm^2$ )

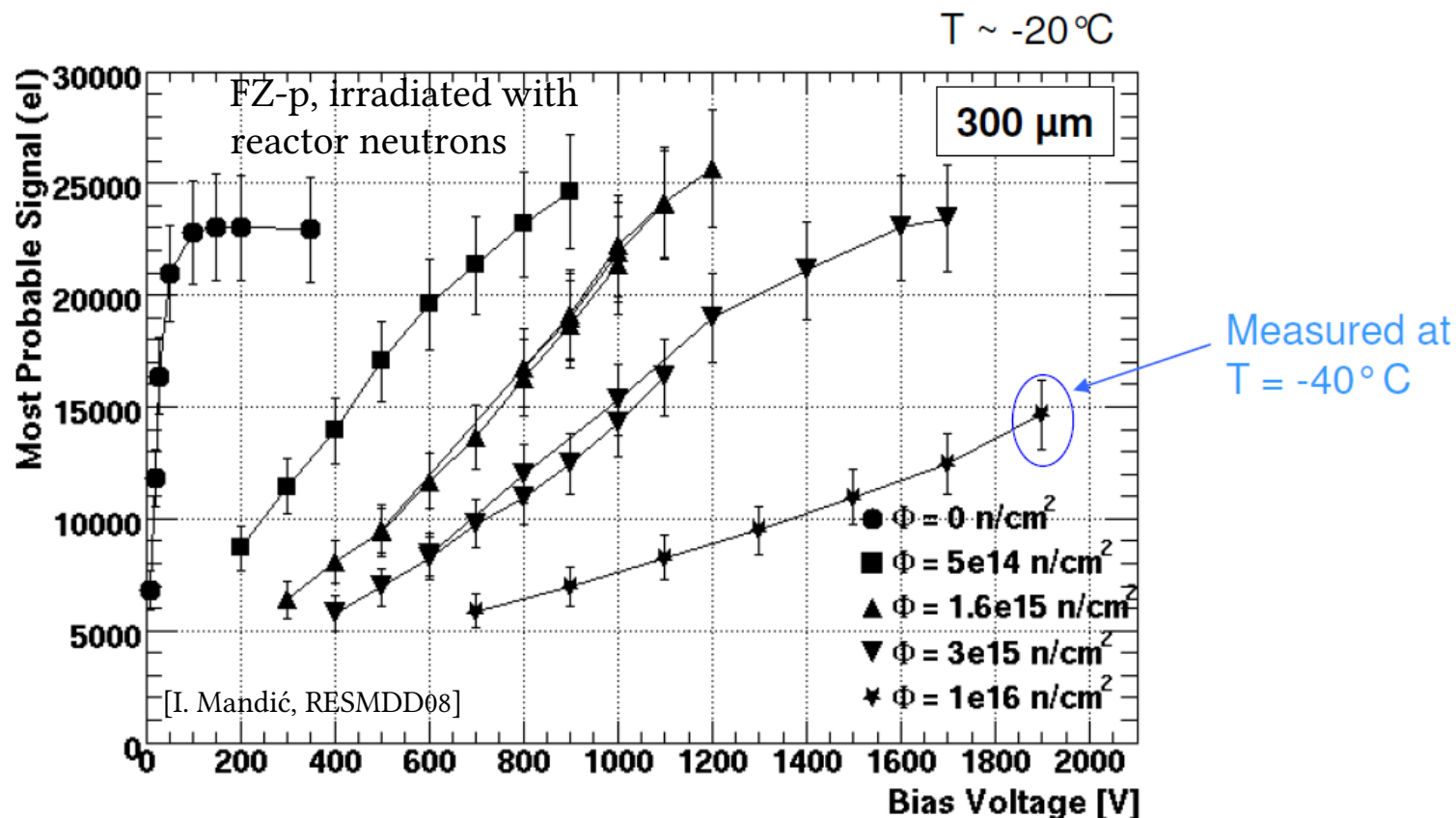
Drift velocity profile



# p-type devices: CM

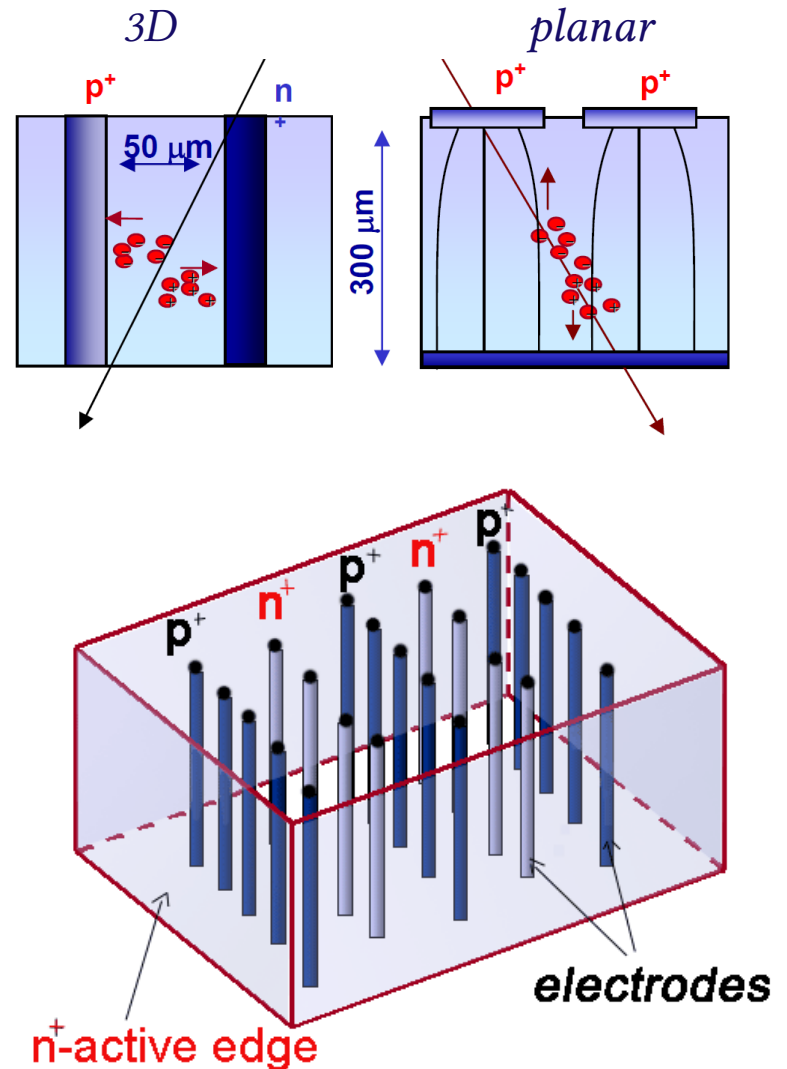
## CCE measurements of irradiated FZ p-type strip devices

- ◆ 100% CCE observed even after  $3 \times 10^{15}$  n/cm<sup>2</sup>, also even CCE > 100% was observed
- ◆ Extrapolation of charge trapping parameters obtained at lower fluences would predict much lower signal
- ◆ Origin: 'Charge multiplication effects' due to high electric fields close to the strips



# Device engineering: 3D Si sensors

- ◆ **Electrodes:**
  - ◆ narrow columns along detector thickness,
  - ◆ diameter: 10mm, distance: 50 – 100mm
- ◆ **Lateral depletion:**
  - ◆ lower depletion voltage needed
  - ◆ thicker detectors possible
  - ◆ fast signal
  - ◆ radiation hard (short drift path minimizes the trapping)
- ◆ promising results
- ◆ processing of 3D sensors challenging, though many good devices with reasonable production yield produced
- ◆ main drawback is the resulting high channel capacitance
- ◆ 3D sensors will be part of ATLAS IBL detector!



*first proposed by S.I. Parker et al.  
[NIMA 395(1997) 328]*

# New materials: diamond

Property	diamond	Si
Band gap [eV]	5.5	1.12
Intrinsic resistivity @ RT [ $\Omega\text{cm}$ ]	$>10^{11}$	$2.3 \times 10^5$
e(h) mobility [ $\text{cm}^2/\text{Vs}$ ]	1900 (2300)	1350(480)
e(h) sat. velocity [ $\text{cm/s}$ ]	$1.3(1.7) \times 10^5$	$1.1(0.8) \times 10^5$
Dielectric constant	5.7	11.9
Displacement energy [eV/atom]	43	13-20
Thermal conductivity [W/m K]	$\sim 2000$	150
Energy to create e-h pair [eV]	13	3.61
MIP Ionization loss [Mev/cm]	4.7	3.21
Avrg. MIP signal/100 $\mu\text{m}$ [ $e_0$ ]	3602	8892

$\Rightarrow$  low leakage current  
(low noise, no cooling)

$\Rightarrow$  fast signal

$\Rightarrow$  low capacitance

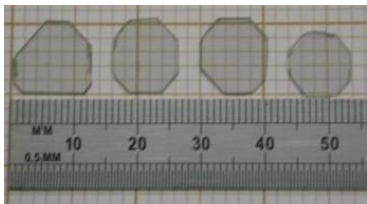
$\Rightarrow$  radiation hard

$\Rightarrow$  heat spreader

$\Rightarrow$  low signal



poly-CVD (16 chip  
ATLAS pixel module)



single crystal CVD  
diamond (few cm)

*Diamond sensors heavily  
used in LHC experiments  
for Beam Monitoring*

# ATLAS: BCM and BLM

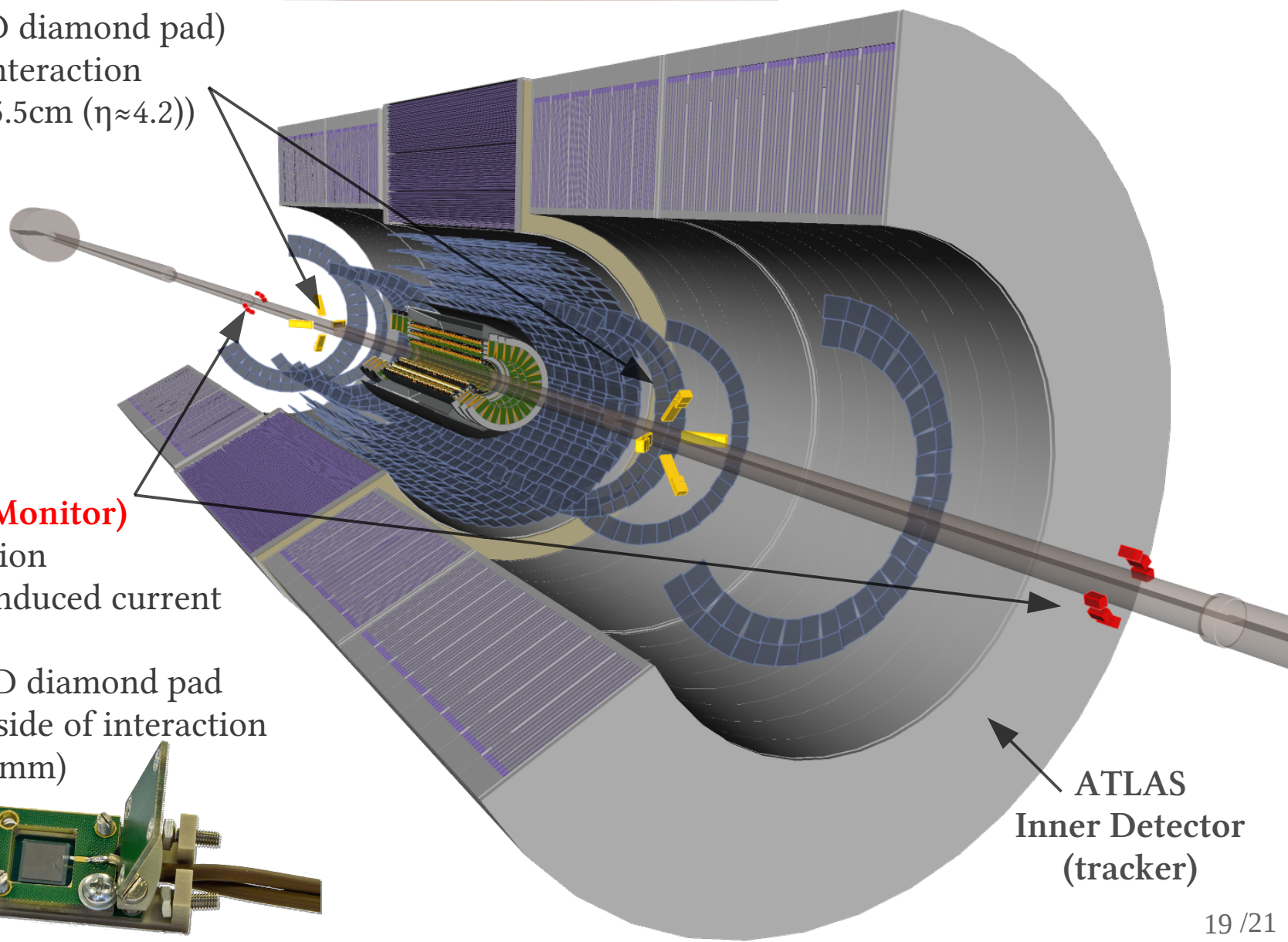
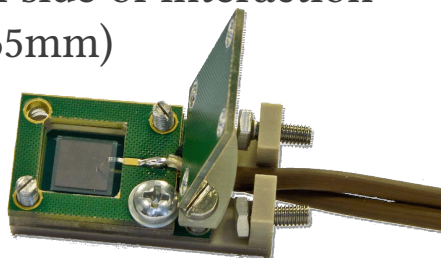
## BCM (Beam Conditions Monitor)

- ◆ purpose: protection, luminosity
- ◆ based on TOF measurement
- ◆ 4 modules (pCVD diamond pad) on each side of interaction  
( $z = \pm 183.8\text{cm}$ ,  $r = 5.5\text{cm}$  ( $\eta \approx 4.2$ ))



## BLM (Beam Loss Monitor)

- ◆ purpose: protection
- ◆ based on beam induced current measurement
- ◆ 6 modules (pCVD diamond pad sensor) on each side of interaction  
( $z \sim 3450\text{mm}$ ,  $r \sim 65\text{mm}$ )

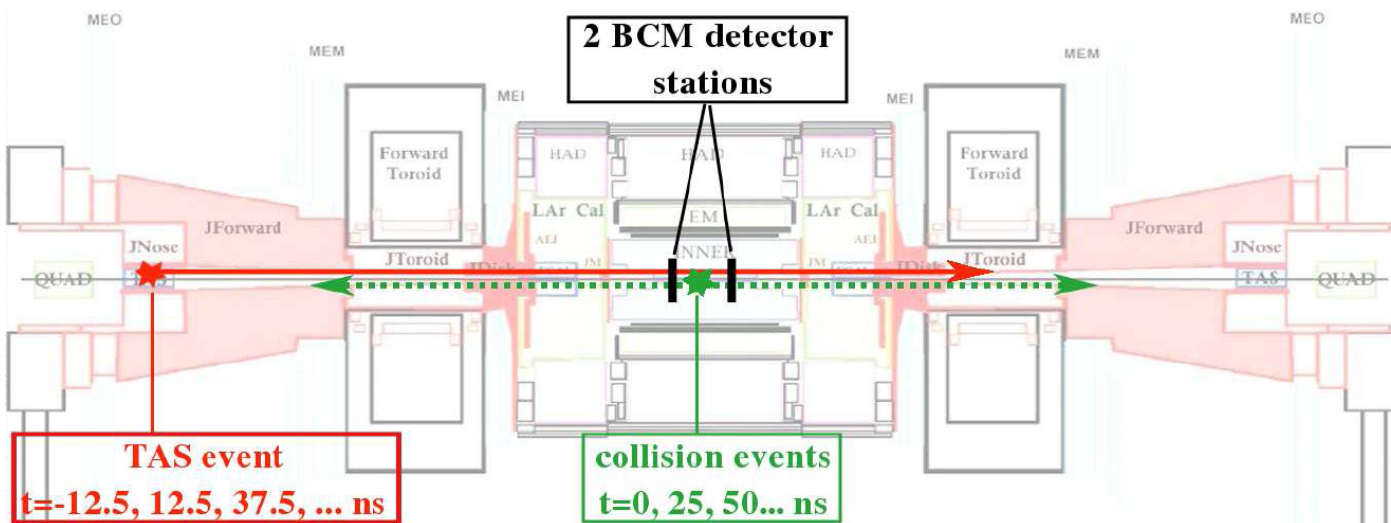
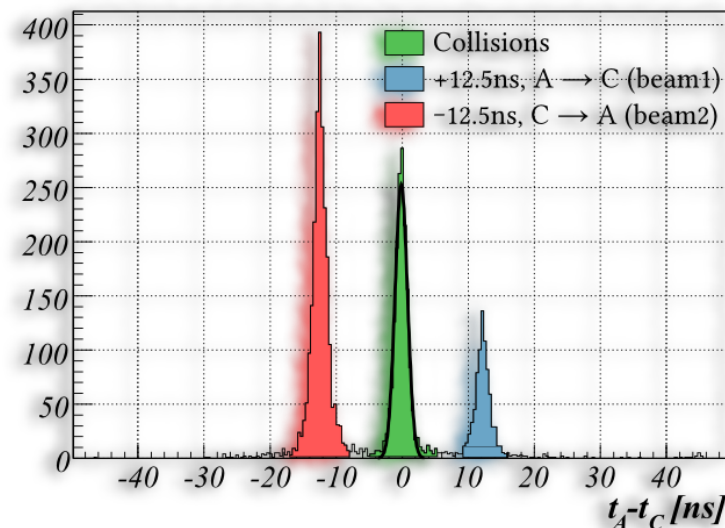




# ATLAS BCM: principle of operation

Time of flight measurement to distinguish between collisions and background events (beam – gas, halo, TAS scraping)

- ◆ measurement every proton bunch crossing (25ns)
- ◆ 2 detector stations at  $z = \pm 1.9\text{m}$
- ◆ particles from collisions reach both stations at the same time ( $\sim 6\text{ns}$  after collisions)
- ◆ secondary particles from downstream background interactions reach nearest station 12.5ns before particles from collisions ( $\sim 6\text{ ns}$  before collisions)
- ◆ use coincident “in time hits” to monitor luminosity
- ◆ use “out of time hits” to identify background events



## Requirements:

- ◆ fast and radiation hard detector & electronics:
  - ◆ rise time  $\sim 1\text{ns}$
  - ◆ pulse width  $\sim 3\text{ns}$
  - ◆ baseline restoration  $\sim 10\text{ns}$
  - ◆ ionization dose  $\sim 0.5\text{ MGy}$ ,
  - ◆  $10^{15}\text{ particles/cm}^2$  in 10 years
- ◆ MIP sensitivity



# Sensors for HL-LHC

## Fluences $\Phi_{eq} < 10^{15} \text{cm}^{-2}$ (outer layers – strip sensors)

- Underdepletion is dominant cause for CCE degradation
- n-MCz silicon detectors**: good performance in mixed fields due to compensation of charged hadron and neutron damage (more work needed)
- p-type Si microstrip detectors**: encouraging results (“base line option” for the ATLAS SCT upgrade)

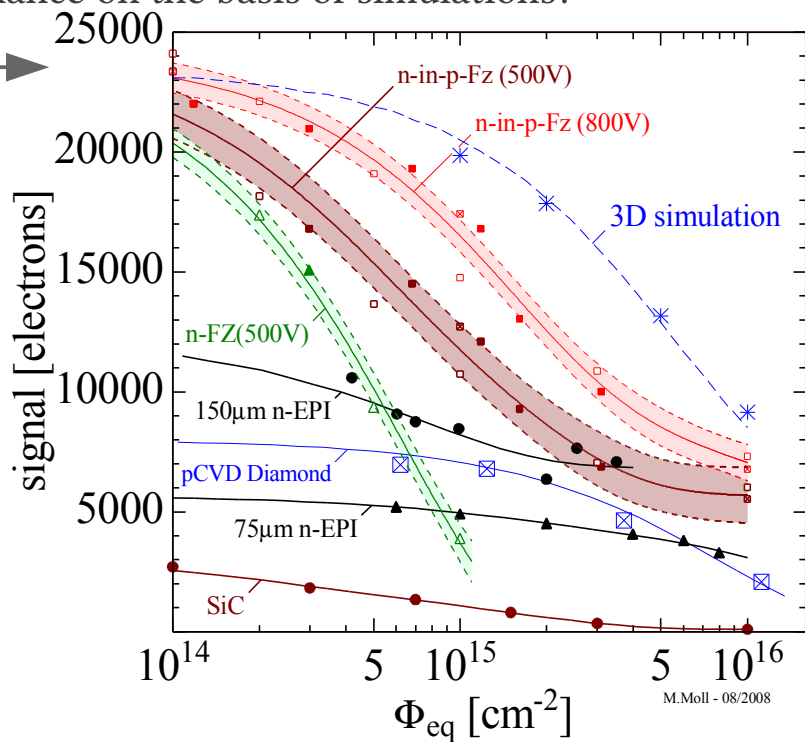
## Fluences $\Phi_{eq} > 10^{15} \text{cm}^{-2}$ (innermost tracking layers – pixel sensors)

- CCE degradation mostly due to **trapping** -> active thickness is significantly reduced
- Collection of electrons at electrodes essential: Use n-on-p or n-on-n detectors!
- Presently three options under investigation: **planar Si (thin, p-type), 3D Si, Diamond**

## Questions to explore:

- Can we control multiplication effects in order to profit from them?
- Can we profit from compensation effects in mixed fields (i.e. MCz-n)?
- Can we understand detector performance on the basis of simulations?

A comparison of technologies in terms of collected charge (signal)



### Note:

- measurement at partly different conditions...
- only an indication of what could be used
- for specific applications SNR crucial! (also important: efficiency, availability, price, reliability, cooling, track resolution...)

## Silicon Sensors

- p-in-n (EPI), 150  $\mu\text{m}$  [7,8]
- ▲ p-in-n (EPI), 75  $\mu\text{m}$  [6]
- n-in-p (FZ), 300  $\mu\text{m}$ , 500V, 23GeV p [1]
- n-in-p (FZ), 300  $\mu\text{m}$ , 500V, neutrons [1]
- n-in-p (FZ), 300  $\mu\text{m}$ , 500V, 26MeV p [1]
- n-in-p (FZ), 300  $\mu\text{m}$ , 800V, 23GeV p [1]
- n-in-p (FZ), 300  $\mu\text{m}$ , 800V, neutrons [1]
- n-in-p (FZ), 300  $\mu\text{m}$ , 800V, 26MeV p [1]
- ▲ p-in-n (FZ), 300  $\mu\text{m}$ , 500V, 23GeV p [1]
- △ p-in-n (FZ), 300  $\mu\text{m}$ , 500V, neutrons [1]
- \* Double-sided 3D, 250  $\mu\text{m}$ , simulation! [5]

## Other materials

- SiC, n-type, 55  $\mu\text{m}$ , 900V, neutrons [3]
- Diamond (pCVD), 500  $\mu\text{m}$  [4] (RD42)

### References:

- [1] p/n-FZ, 300  $\mu\text{m}$ , (-30°C, 25ns), strip [Casse 2008]
- [2] p-FZ, 300  $\mu\text{m}$ , (-40°C, 25ns), strip [Mandic 2008]
- [3] n-SiC, 55  $\mu\text{m}$ , (2us), pad [Moscato 2006]
- [4] pCVD Diamond, scaled to 500  $\mu\text{m}$ , 23 GeV p, strip [Adam et al. 2006, RD42]
- [5] 3D, double sided, 250  $\mu\text{m}$  columns, 300  $\mu\text{m}$  substrate [Pennicard 2007]
- [6] n-EPI, 75  $\mu\text{m}$ , (-30°C, 25ns), pad [Kramberger 2006]
- [7] n-EPI, 150  $\mu\text{m}$ , (-30°C, 25ns), pad [Kramberger 2006]
- [8] n-EPI, 150  $\mu\text{m}$ , (-30°C, 25ns), strip [Messineo 2007]